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Applicant(s): ALI SHAKOURI ET AL.

Docket No.

UC01-161-2

Serial No.

10/039,290

Filing Date

January 4, 2002

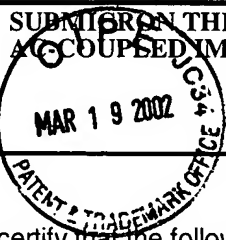
Examiner

Group Art Unit

2877

Invention: SUBMITTER THERMAL IMAGING METHOD AND ENHANCED RESOLUTION (SUPER-RESOLVED)
AND COUPLED IMAGING FOR THERMAL INSPECTION OF INTEGRATED CIRCUITS

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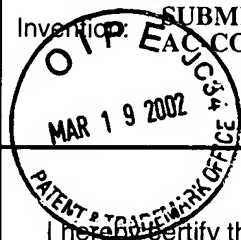
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2877Invention: **SUBMICRON THERMAL IMAGING METHOD AND ENHANCED RESOLUTION (SUPER-RESOLVED) EAC COUPLED IMAGING FOR THERMAL INSPECTION OF INTEGRATED CIRCUITS**

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